


Form PTO-1449
(REV. 1/06)

US Dept. of Commerce
PATENT & TRADEMARK OFFICE

ATTY DOCKET NO.
128865

APPLICATION NO.
10/587,268

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANTS
Hiroaki TAKAIWA et al.

FILING DATE
July 26, 2006

GROUP
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